

Mask Layout Challenges for Silicon Photonics

Session IV: Design Automation and Methodologies

MARCEL VAN DER VLIET

DESIGN, AUTOMATION & TEST IN EUROPEAN CONFERENCE OPTICAL/PHOTONIC INTERCONNECTS FOR COMPUTING SYSTEMS MARCH $31^{\rm ST}$ 2017





Outline

- PhoeniX Software
- Discretization
- Design Intent
- Design Rule Checks
- PDA EDA Integration



PhoeniX Software

- Chip & Mask Layout
- Design Rule Checking
- Process Flow Visualization
- Mode & Propagation Simulations
- Photonic Building Block platform
- EDA & PDA 3rd party interfaces
- PDKs and packaging templates to facilitate manufacturability

PIC Design Suite

OptoDesigner

Training & Support

- In-depth photonics design training
- MPW training with partners
- o Global support team
- On-site training and support
- PDK development

- Reduced time to market
- Improved innovation process
- Flexibility in design flowWorks with all technologies
- Increased efficiency
- Scalability of design & manufacturing process

Customer Impact



Service Partners



AIM

We enable the easy and cost-effective realization of integrated photonics chips and systems

Partnerships

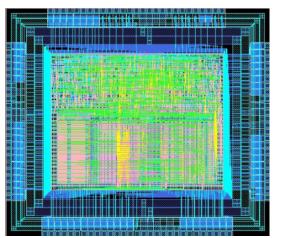
with foundries, software vendors, design houses, universities, ...



EDA versus PDA



Manhattan versus "Erice" patterns

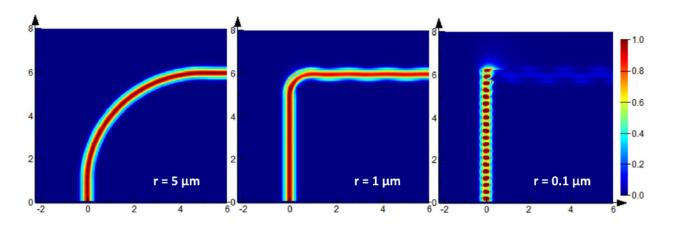




Manhattan versus curvilinear patterns



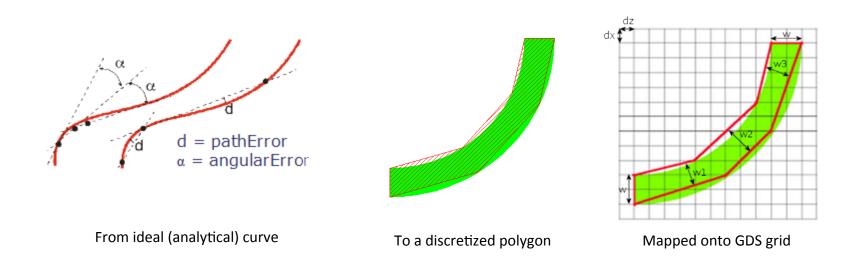
Non-Manhattan / curvilinear design



Waveguide routing requires a curved format instead of rectilinear/Manhattan-style routing to ensure that light stays in a waveguide. Simulation of a curved waveguide with different radii. Image courtesy of Lumerical Solutions, Inc.



Curve Discretization



Need for tools to translate ideal curves (Design Intent) into discretized polygons, controlling phase relations



Mask layout impacts:

Losses

- Obtaining smooth curves and side-walls
- Mask orientation of waveguides (due to writing direction of mask)

Back Reflection

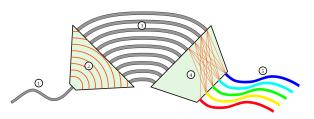
- Smooth curves and side-walls
- Limits on angle changes (radius)

Phase Changes

- Width (and height) control of waveguides (1 nm -> 125 GHz)
 - Changes in optical path-length



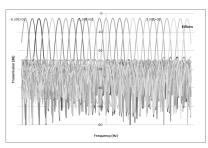
Impact of optical path-length

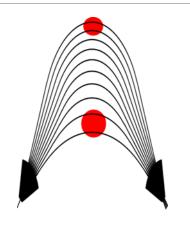


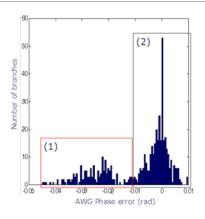
Example: Arrayed Waveguide Grating

It is in fact a (de)multiplexer for light. Different colors (data streams) are filtered into different waveguides.

The geometry determines the optical performance, and can be calculated through simulations from specifications like bandwidth, number of output channels, channel spacing, etc.







Phase errors resulting from:

- (1) errors due to mismatches in the optical path lengths in the branches in the array
- (2) stochastical errors from fabrication variations



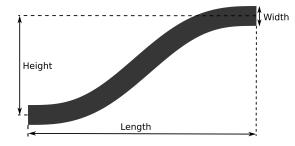
Generic (EDA) scripting languages

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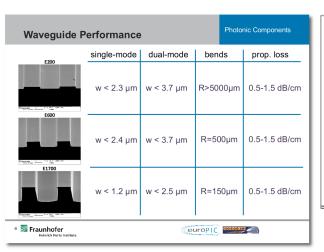
Example of the description of a **sine-bend** taken from a Cadence Virtuoso (SKILL) p-cell as used in a silicon photonics PDK

Same applies to Mentor Graphics AMPLE or generic languages like Matlab, Python, ...

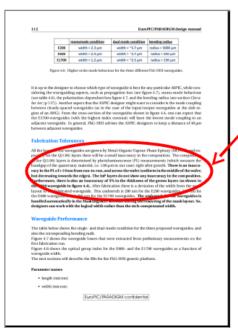


Design for Manufacturing

Fabrication -> cross-section -> performance





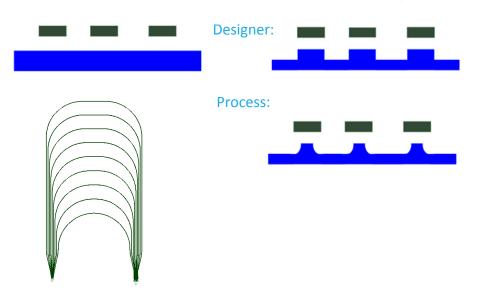


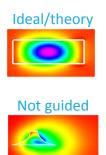
After fabrication there is a deviation of the width from the mask layout to the fabricated waveguide. This underetch is 200 nm for the E200 waveguides, 300 nm for the E600 waveguides, and 500 nm for the E1700 waveguides.



From Design Intent to GDSII

• Fabrication \rightarrow cross-section \rightarrow performance

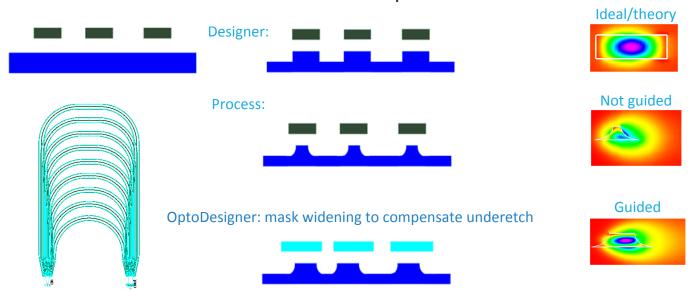






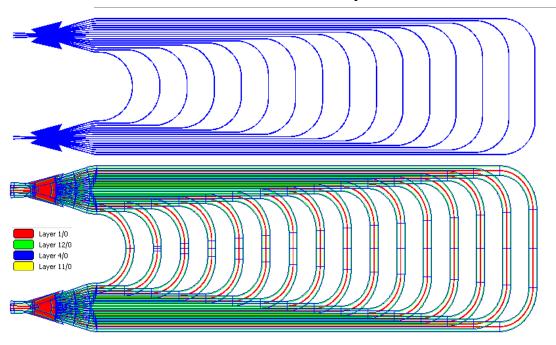
From Design Intent to GDSII

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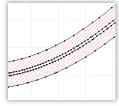
Real life example for Design Intent



AWG example: from intended waveguide or "logical" design into actual mask or "GDS" design to fabricate with the correct waveguide dimensions (cross section)

From design intent to final mask layout:

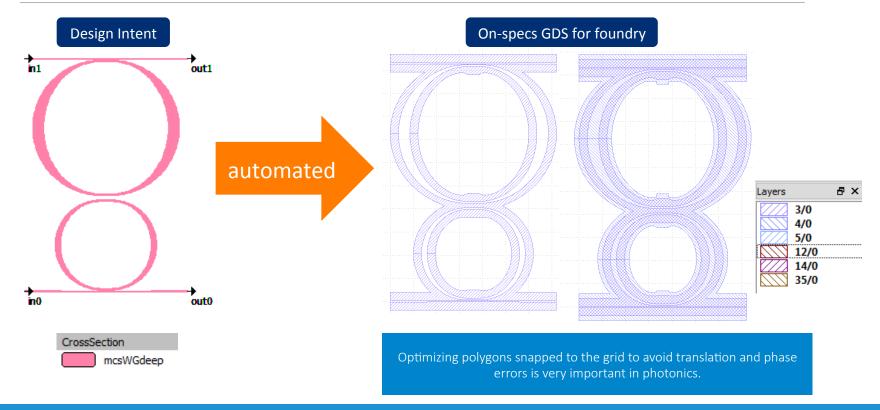
- Calculating the required shapes, given the design intent and the fabrication information
- Turning these into polygons, given a maximum allowed path error
- Placing the polygons into the required mask layers, including sizing, inversion, boolean operations, etc.
- Checking design rules
- Exporting mask (GDS2) files







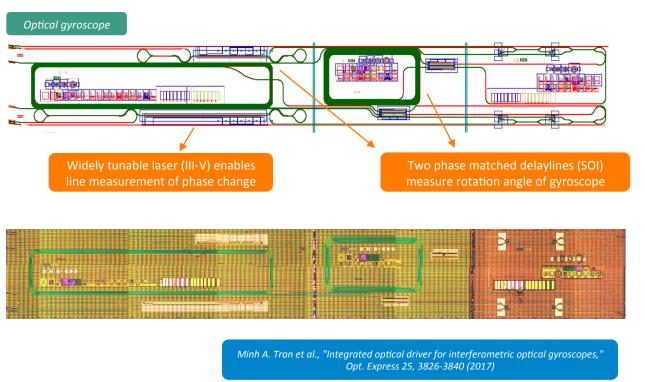
Using Design Intent in the UCSB PDK

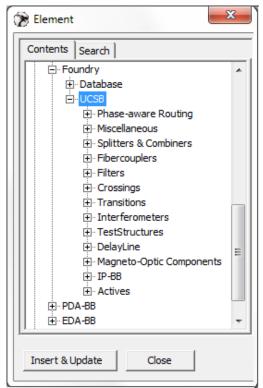






Heterogeneous SOI & III-V Integration — PDK Available

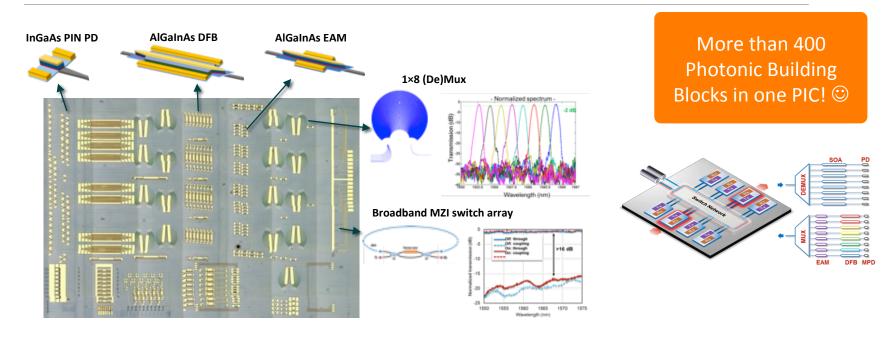








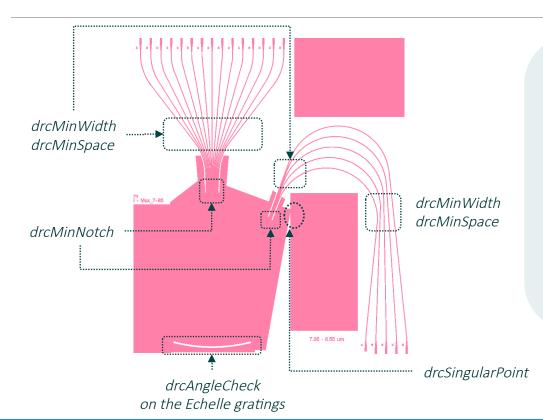
UCSB Heterogeneous SOI & III-V Integration — PDK available



8 × 8 × 40 Gbps fully integrated silicon photonic network on chip, Zhang et al., 2334-2536/16/070785-02 Journal, 2016 Optical Society of America



DRC Design Rule Checks

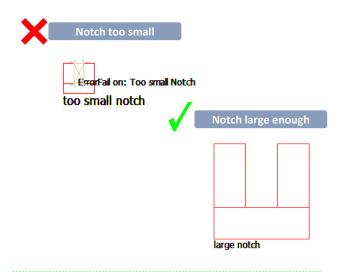


Fabrication errors can lead to high costs and unwanted delays, however, they can be prevented by using verification and Design Rule Checks (DRC).

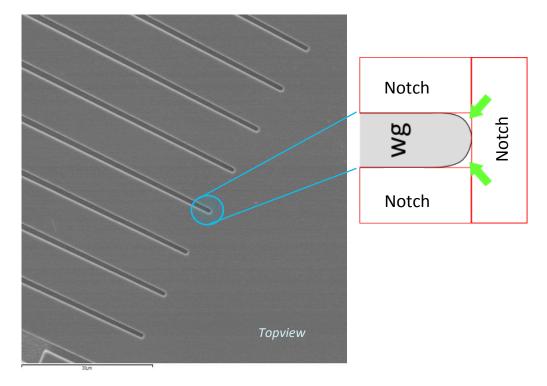
Both for academic research as well as commercial product development, it is a key step in the whole design flow from initial concept to manufacturable mask layout.



DRC example Notch Check



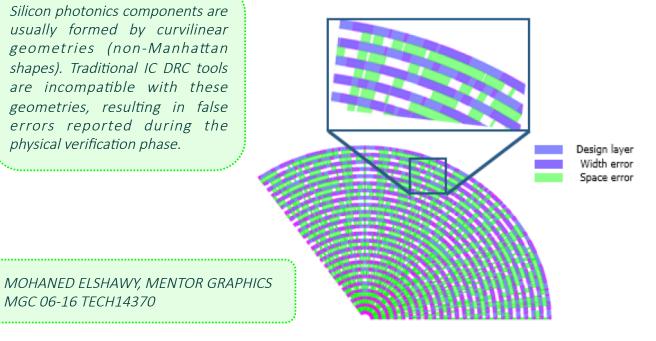
Rounding of a square feature (the end of the waveguide) as a result of the distance to surrounding features (or non etched surfaces)

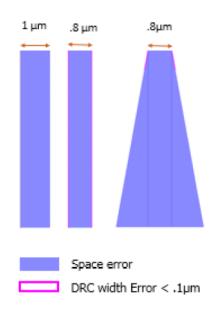




Challenges for Calibre

Silicon photonics components are usually formed by curvilinear geometries (non-Manhattan shapes). Traditional IC DRC tools are incompatible with these geometries, resulting in false errors reported during the physical verification phase.

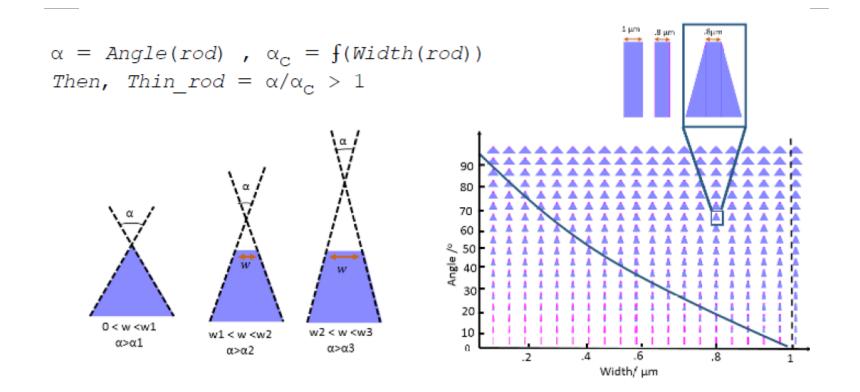




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Conditional and multidimensional DRC

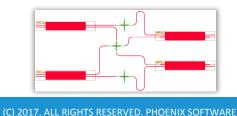


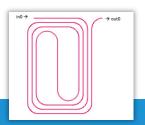


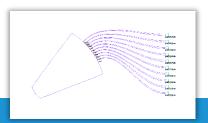
Situation today

- Challenges we see customers and foundries running into:
 - Increasing complexity of PIC designs
 - Significant waveguide routing challenges
 - Limited circuit simulation capabilities with validated models
 - Design verification: design rule checking and layout vs schematic
 - Co-design of electronics and photonics

To support the industry in the transition from research to commercial product development, we need integrated design flows supporting a design for manufacturability design strategy, making use of strengths of both PDA as well as EDA tools



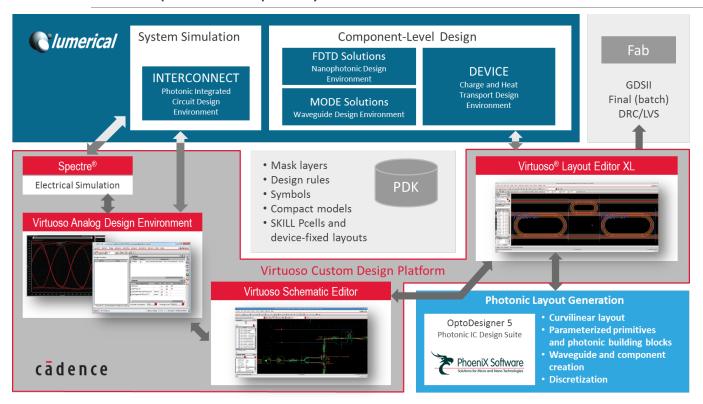






EDA – PDA integration

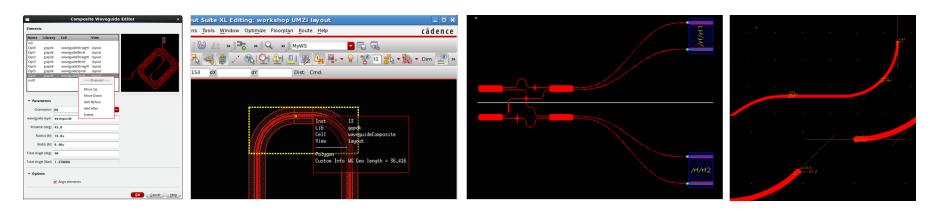
Example of 3-party collaboration



- Collaboration announced in December 2015
- Schematic Driven
 Layout flow,
 centered around a
 PDK approach



PhoeniX Software's Virtuoso integration with PDA-Link access point into all PhoeniX Software's PIC design routines

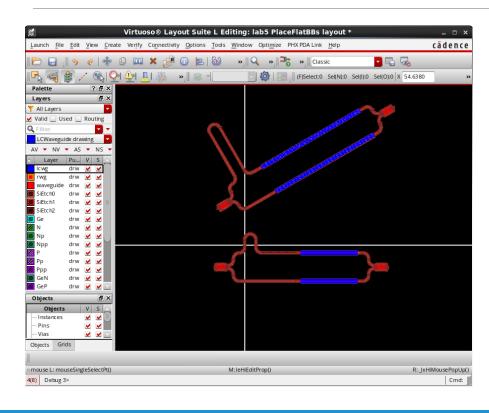


All photonics parts are provided by PhoeniX Software technology

Overcoming the grid-based "Manhattan" design limitations in traditional IC design tools



All angle in Virtuoso



- Fully Parameterized
 - Path Length Difference
 - Modulator Length
 - ...
- All Angle



Summary

- Discretization impacts device performance
 - Good algorithms required
- Technology dependencies can create complex tasks
 - Need good PDKs
 - Hybrid PDK design environment
- Design rule checks of EDA are not sufficient
- Need integration between EDA and PDA tools



www.phoenixbv.com

marcel@phoenixbv.com

